IN THE CLAIMS:

Please amend the claims as follows.

1. (Original) A method for manufacturing an optical device, comprising:

coating a substrate with a resin thin layer, wherein temperature of the resin thin layer is controlled lower than a polymerization reaction starting temperature thereof and the resin is not substantially polymerized;

heating the resin thin layer to a temperature higher than polymerization reaction starting temperature and glass-transition temperature but lower than a thermal decomposition starting temperature of the resin so that the resin thin layer is polymerized on the substrate to form a resin thin film thereon;

pressing a stamp having an inverted micro-asperity pattern against the resin thin film such that a micro-asperity pattern is formed on a surface of the resin thin film;

cooling the resin thin film to a temperature lower than the glass-transition temperature; and

separating the stamp from the resin thin film.

2. (Original) The method according to claim 1, wherein the stamp is pressed against the resin thin film a plurality of times.

3. (Original) The method according to claim 1, wherein the substrate is provided with an alignment mark thereon such that the stamp can be placed on the substrate in a manner that the alignment mark provided on the substrate matches a reference position of the stamp.

4. (Original) The method according to claim 1, wherein the micro-asperity pattern is formed on the surface of the resin thin film in an inert gas atmosphere.

5. (Original) The method according to claim 1, wherein the micro-asperity pattern is formed on the surface of the resin thin film in a chamber, and pressure inside the chamber is maintained lower than atmospheric pressure.

6. - 29. (Canceled)

30. (Original) A method for manufacturing a reflection plate, comprising:

coating a substrate with a resin thin layer, wherein temperature of the resin thin layer is controlled lower than a polymerization reaction starting temperature and the resin is not substantially polymerized;

heating the resin thin layer to a temperature higher than polymerization starting temperature and glass-transition temperature but lower than a thermal decomposition starting temperature of the resin so that the resin thin layer is polymerized on the substrate to form a resin thin film;

pressing a stamp having an inverted micro-asperity pattern against the resin thin film such that a micro-asperity pattern is formed on a surface of the resin thin film;

cooling the resin thin film to a temperature lower than the glass-transition temperature;

separating the stamp from the resin thin film; and

forming a reflection film and an alignment film on the resin film having the micro-asperity pattern thereon..

31. (Canceled)